

Abstract of the Disclosure

A method of forming a film on a substrate using Group IVB, VB, or VIB metal complexes. The methods are particularly suitable for the preparation of semiconductor structures using chemical vapor deposition techniques and systems.

"EXPRESS MAIL" MAILING LABEL NUMBER

EL 77690.367645

DATE OF DEPOSIT:

25 May 2001

DATE OF DEPOSIT: 23 May 2001
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